Docket No. 03500.015382.

Examiner: Brian L. Mutschler

Group Art Unit: 1753

Date: October 8, 2004

In re Application of:

TAKAHARU KONDO, E'

Application No.: 09/866,665

Filed: May 30, 2001

For: SILICON-TYPE THIN FILM FORMATION PROCESS, SILICON TYPE THIN FILM, AND PHOTOVOLTAIC DEVICE

Mail Stop Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

Transmitted herewith is an Amendment in the above-identified application.

| X | No additional fee is required.

The fee has been calculated as shown below

CLAIMS AS AMENDED								
	(2) CLAIMS REMAINING AFTER AMENDMENT		(4) HIGHEST NO. PREVIOUSLY PAID FOR	(5) PRESENT EXTRA	RATE	ADDITIONAL FEE		
TOTAL CLAIMS	* 14	MINUS	** 21	= 0	x \$9 \$18	\$0.00		
INDEP. CLAIMS	* 3	MINUS	***	= 0	x \$44 \$88	\$0.00		
Fee for Mu	\$0.00							
	\$0.00							

If the entry in Column 2 is less than the entry in Column 4, write "0" in Column 5.

If the "Highest Number Previously Paid For" IN THIS SPACE is less than 20, write "20" in this space. If the "Highest Number Previously Paid For" IN THIS SPACE is less than 3, write "3" in this space.

	Verified Statement claiming small entity status is enclosed, if not filed previously.					
	A check in the amount of \$ is enclosed.					
	Charge \$ to Deposit Account No. 06-1205. A duplicate copy of this sheet is enclosed.					
X	Any prior general authorization to charge an issue fee under 37 C.F.R. 1.18 to Deposit Account No. 06-1205 is hereby revoked. The Commissioner is hereby authorized to charge any additional fees under 37 C.F.R. 1.16 and 1.17 which may be required during the entire pendency of this application, or to credit any overpayment, to Deposit Account No. 06-1205. A duplicate copy of this paper is enclosed.					
	A check in the amount of \$ to cover the fee for a month extension is enclosed.					
	A check in the amount of \$ to cover the Information Disclosure Statement fee is enclosed.					
X	Applicants' undersigned attorney may be reached in our New York office by telephone at (212) 218-2100. All correspondence should continue to be directed to our address given below.					
	Respectfully submitted,					
	1					

Peter G. Thurlow

Attorney for Applicants Registration No.: 47,138

FITZPATRICK, CELLA, HARPER & SCINTO 30 Rockefeller Plaza New York, New York 10112-3800 Facsimile: (212) 218-2200

NY\_MAIN 457657v1



## **PATENT APPLICATION**

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:		)	Francisco Deica I. Matalilar	
ΓΑΚΑΗARU KONDO, ET AL.		: )	Examiner: Brian L. Mutschler	
Application No.: 09/866,665		:	Group Art Unit: 1753	
Filed	: May 30, 2001	: ) ·		
For:	SILICON-TYPE THIN FILM FORMATION PROCESS, SILICON TYPE THIN FILM, AND PHOTOVOLTAIC DEVICE	) : )	October 8, 2004	
Com P.O.	Stop Amendment missioner for Patents Box 1450 andria, VA 22313-1450			

## **AMENDMENT**

Sir:

In response to the Office Action dated July 8, 2004, please amend the above-identified application as follows. The claim amendments are reflected in the listing that begins at page 2, and the Remarks begin at page 6.

I hereby certify that this correspondence is being deposited with the United States Postal Service as first-class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on October 8, 2004

| October 8, 2004
| Ottober 9, 2004
| October 9, 2004